

# WAFER HANDLING ROBOT | IWH

## WITH 2-LINK DUAL ARM AND BODY SERIES 3

### CHARACTERISTICS

- excellent structural rigidity
- wafer handling up to 300mm
- maximum reliability and precision
- easy connection of a linear track to the robot controller
- very smooth running
- backlash free Harmonic Drive® gears
- absolute or incremental encoder
- integrated 2-channel vacuum display (standard controller)
- fully integrated software adjustable vacuum sensors (advanced controller)
- including „Standard“ or „Advanced“ controller and software
- ISO 1 clean-room environment compatible
- MTBF: > 50,000 operating hours
- option: 2 flip modules iFM-300-3

### SPECIFICATIONS

|                |   |                             |
|----------------|---|-----------------------------|
| Repeatability  | T   | ±0.02°                      |
|                | R   | ±0.02 mm                    |
|                | Z   | ±0.02 mm                    |
| Working range  | Z   | 7", 10", 13", 15", 17", 21" |
|                | radial  | 10", 14"                    |
|                | theta   | 500°                        |
| Payload        | up to 1.25 kg (per arm)   |                             |
| Maximum speed  | T   | 360°/s                      |
|                | R   | 1,100 mm/s                  |
|                | Z   | 425 mm/s                    |
| Power supply   | 115 – 230 VAC<br>50 – 60 Hz<br>500 VA (standard)<br>550 VA (advanced) |                             |
| Main interface | RS-232 [DB9],<br>Ethernet [RJ-45]                                     |                             |
| Weight         | approx. 25 – 40 kg  |                             |



IWH F-3  
dual arm robot



Vacuum displays  
with standard controller

### DIMENSIONS

